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**APPLICANTS**

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**\*\* CONTINUING DATA \*\*\*\*\***

None

**\*\* FOREIGN APPLICATIONS \*\*\*\*\***

JAPAN 2002-330683 11/14/2002  
 JAPAN 2003-372019 10/31/2003

**IF REQUIRED, FOREIGN FILING LICENSE GRANTED****\*\* 02/06/2004**

Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWING</b> 10	<b>TOTAL CLAIMS</b> 31	<b>INDEPENDENT CLAIMS</b> 5
35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met				
Verified and Acknowledged <u>Allowance</u>	Examiner's Signature <u>[Signature]</u>	Initials		

**ADDRESS**

22852

**TITLE**

Semiconductor wafer treatment method, semiconductor wafer inspection method, semiconductor device development method and semiconductor wafer treatment apparatus

<b>FILING FEE RECEIVED</b> 2070	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees
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